PTO/SB/44 (04-04)
Approved for use through 04/30/2007. OMB 0651-0033
U.S. Patent and Trademark Office; U.S. DEPARTMENT OF COMMERCE

UNITED STATES PATENT AND TRADEMARK OFFICE
CERTIFICATE OF CORRECTION

PATENT NO.: 6,998,156 B2

APPLICATION NO.: 10/059,978

ISSUED DATE: February 14, 2006

INVENTOR(S): Daniel Bubb, James Horwitz, John Callahan, Richard Haglund, Jr., and Michael Papantonakis

It is certified that an error appears or errors appear in the above-identified patent and that said Letters Patent is hereby corrected as shown below:

Column 8:

Lines 58-67, "1. A method for transferring a material onto a substrate comprising the steps of:

(a) directing light of a wavelength in the infrared region which is resonant with a vibrational mode at a target starting material,
(b) vaporizing the target material with the light without decomposing, the target material, and
(c) depositing the vaporized material on a substrate in solid form that is essentially same chemically as the starting target material." should read

-- 1. A method for transferring a material onto a substrate comprising the steps of:

(a) directing light of a wavelength in the infrared region which is resonant with a vibrational mode of a target starting material,
(b) vaporizing the target starting material with the light without decomposing the target starting material, and
(c) depositing the vaporized material on a substrate in solid form that is essentially same chemically as the target starting material. --

Column 9:

Lines 10-18, "6. The method of claim 1 including the steps of subjecting the target and the substrate to an environment selected from the group consisting of sub-atmospheric, atmospheric and above atmospheric pressure and locating the target and the substrate in the vicinity of each other so that the vaporized material from the target can be deposited on the substrate by free fall; and the temperature of the substrate is such that the vaporized material settles on the substrate and becomes solid." should read

-- 6. The method of claim 1 including the steps of subjecting the target starting material and the substrate to an environment selected from the group consisting of sub-atmospheric, atmospheric and above atmospheric pressure and locating the target starting material and the substrate in the vicinity of each other so that the vaporized material from the target starting material can be deposited on the substrate by free fall; and the temperature of the substrate is such that the vaporized material settles on the substrate and becomes solid. --

MAILING ADDRESS OF SENDER:

PATENT NO. 6,998,156 B2

No. of additional copies

Tim Tingkang Xia
MORRIS, MANNING & MARTIN, LLP
1600 Atlanta Financial Center
3343 Peachtree Road, N.E.
Atlanta, Georgia 30326-1044